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MEMS

The background of the cover is a detailed, artistic illustration in a monochromatic reddish-brown color. It features a complex arrangement of interlocking gears of various sizes, some with multiple teeth. A network of thin, curved lines, resembling wires or microfluidic channels, weaves through the gears. Several small, polished spheres are scattered throughout the composition, some resting on the gears and others suspended in the air. The overall effect is one of intricate mechanical complexity and precision.

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